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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/672,013	09/26/2003	Seong Deok Ahn	2013P107	7684	
8791	7590 08/01/2005		EXAMINER		
	SOKOLOFF TAYLOR	BUEKER, RICHARD R			
SEVENTH I		ART UNIT	PAPER NUMBER		
LOS ANGELES, CA 90025-1030			1763		
			DATE MAILED: 08/01/2003	5	

Please find below and/or attached an Office communication concerning this application or proceeding.

		Applicat	ion No.	Applicant(s)	-			
Office Action Cummon.		10/672,0)13 	AHN ET AL.	•			
	Office Action Summary	Examine	er ,	Art Unit				
		Richard I		1763	·			
Period fo	The MAILING DATE of this commun or Reply	nication appears on th	ne cover sheet with	the correspondence add	ress			
THE - Exte after - If the - If NC - Failt Any	ORTENED STATUTORY PERIOD F MAILING DATE OF THIS COMMUN nsions of time may be available under the provisions SIX (6) MONTHS from the mailing date of this comr o period for reply specified above is less than thirty (3 period for reply is specified above, the maximum so tre to reply within the set or extended period for reply reply received by the Office later than three months ed patent term adjustment. See 37 CFR 1.704(b).	IICATION. s of 37 CFR 1.136(a). In no e munication. 30) days, a reply within the sta tatutory period will apply and v y will, by statute, cause the ap	atutory minimum of thirty (3 will expire SIX (6) MONTHS oplication to become ABANI	y be timely filed 10) days will be considered timely. S from the mailing date of this con DONED (35 U.S.C. § 133).				
Status		·			-			
1)	Responsive to communication(s) file	ed on .	•					
	This action is FINAL . 2b)⊠ This action is non-final.							
3)	<u> </u>							
• –	closed in accordance with the practice under Ex parte Quayle, 1935 C.D. 11, 453 O.G. 213.							
Disposit	ion of Claims							
4)⊠	Claim(s) 1-14 is/are pending in the	application.		•				
	4a) Of the above claim(s) is/are withdrawn from consideration.							
·=	5) Claim(s) is/are allowed.							
6)🖂	7)							
7)	Claim(s) is/are objected to.							
8)□	Claim(s) are subject to restrict	ction and/or election	requirement.					
Applicati	ion Papers	. .			•			
9)□	The specification is objected to by the							
	9) The specification is objected to by the Examiner. I0) The drawing(s) filed on is/are: a) accepted or b) objected to by the Examiner.							
٠٠/ت	Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).							
	Replacement drawing sheet(s) including				₹ 1 121/d)			
11)	The oath or declaration is objected to	•		•	• •			
				×				
Priority (ınder 35 U.S.C. § 119			•				
	Acknowledgment is made of a claim ☐ All b) ☐ Some * c) ☐ None of:	for foreign priority ur	nder 35 U.S.C. § 1	19(a)-(d) or (f).				
	1. ☐ Certified copies of the priority	documents have be	en received.					
	2. Certified copies of the priority		• •		,			
3. Copies of the certified copies of the priority documents have been received in this National Stage								
	application from the International Bureau (PCT Rule 17.2(a)).							
* 5	See the attached detailed Office action	on for a list of the cert	lified copies not rec	ceived.				
	•							
Attachmen	t(s)							
	e of References Cited (PTO-892)		4) Interview Sum					
	e of Draftsperson's Patent Drawing Review (F			lail Date mal Patent Application (PTO-	152)			
	nation Disclosure Statement(s) (PTO-1449 or r No(s)/Mail Date 9/26/03; 3/7/05	P10/SB/08)	6) Other:	mai r atent Application (PTO-	192)			
			· <u></u>					

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Claim 10 is rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention. In claim 10, the phrases "the transfer lines" and "the valves" lack proper antecedent basis.

Claims 13 and 14 are rejected under 35 U.S.C. 112, first paragraph, as failing to comply with the enablement requirement. The claim(s) contains subject matter which was not described in the specification in such a way as to enable one skilled in the art to which it pertains, or with which it is most nearly connected, to make and/or use the invention. The specification fails to describe or explain the steps of generating first organic source vapors by heating a source chamber containing a first organic source material, and then forming second organic source vapors by heating an additional source chamber containing the first organic material and a second organic material. The specification fails to disclose what the first organic source material and second organic material are. Their compositions are not disclosed, and its unclear whether these first and second materials are required to have different compositions or not. One skilled in the art has no way of knowing what the difference is between the first and second materials, or what the purpose is for depositing two layers containing these two types of materials.

The specification is objected to as failing to provide proper antecedent basis for the claimed subject matter. See 37 CFR 1.75(d)(1) and MPEP § 608.01(o). Correction of the following is required: The specification fails to provide proper antecedent basis for the subject matter of claim 13.

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The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 1, 3, 4, 6-12 are rejected under 35 U.S.C. 102(b) as anticipated by or, in the alternative, under 35 U.S.C. 103(a) as obvious over Jurgensen (WO 01/61071). Jurgensen (WO 01/61071) and Jurgensen (2003/0054099) are patent family equivalents and Jurgensen (2003/0054099) is used in this office action as an English translation for Jurgensen (WO 01/61071). Jurgensen (see Figs. 1-6) discloses an apparatus for vapor phase deposition including process chamber, temperature controlled substrate holder, showerhead, source chambers for generating organic source vapors, transfer gas (i.e. carrier gas) source and a source heater for evaporating source material in the source chamber. Regarding claim 3, Jurgensen (see Fig. 8) teaches the use of a bubbler having the transfer gas line extending into the source chamber. Jurgensen teaches that the vaporizer of Fig. 8 can be substituted for any of the source chambers in Figs. 1 and 5. Regarding the purging step in claim 11, Jurgensen teaches (paragraphs 44 and 45) the step of providing a further feed line to feed carrier gas to the showerhead to purge the showerhead plenum when switching

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precursor streams. Also, Jurgensen's three-way valve 43 of Fig. 8 automatically switches carrier gas into the chamber supply line 6 when source gas flow is terminated.

Claims 4-6 and 9 are rejected under 35 U.S.C. 103(a) as being unpatentable over Jurgensen I (WO 01/161071) I Taken in further view of Jurgensen II (WO 02/27064). Jurgensen (WO 02/27064) and Jurgensen (2003/0056720) are patent family equivalents and Jurgensen (2003/0056720) is used in this office action as an English translation for Jurgensen II (WO 02/27064). Jurgensen II teaches the use of a source chamber with a conic gas distributor plate to supply source gas to a vapor coating chamber. It is noted that the vaporizer of Jurgensen II is equivalent to that of DE 10048759 that is cited in paragraph 47 of Jurgensen I.

Claims 11 and 12 are rejected under 35 U.S.C. 103(a) as being unpatentable over Jurgensen I (WO 01/61071) taken in view of Ozias (4,846,102) (col. 2, lines 15-21) who teaches that vapor coating reactors are typically flushed after a coating process. It would have been obvious to one skilled in the art to purge after deposition in Jurgensen's coating apparatus for the desirable purpose of flushing unwanted gases from the reaction chamber.

Claims 11 and 12 are rejected under 35 U.S.C. 103(a) as being unpatentable over Jurgensen I (WO 01/61071) taken in view of Forrest I (5,554,220), Forrest II (6,337,102) and Posa (4,747,367). Forrest I (col. 7, lines 60-67) and Forrest II (col. 3, lines 48-61) teach that it is desirable to switch the gas flows in an OVPD process for depositing plural separate layers, and for that reason it would have been obvious to do so in Jurgensen's OVPD reactor. Furthermore, Posa teaches that a vapor coating

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reactor that is used for depositing plural separate layers should be flushed at the end of each separate gas flow. In view of Posa, it would have been obvious to purge Jurgensen's chamber after the end of each separate gas flow.

Claims 13-14 are rejected under 35 U.S.C. 103(a) as being unpatentable over Jurgensen I (WO 01/61071) taken in view of Forrest I (5,554,220), Forrest II (6,337,102) and Posa (4,747,367) for the reasons given above, and taken in further view of Dauelsberg (WO 01/57289) and Konuma (2002/0030443). Dauelsberg (2003/0056720) is used in this office action as an English translation for Dauelsberg (WO 01/57289). Dauelsberg (see Fig. 9 and para. 49) teaches the use of a vaporizer in which two organic source materials are vaporized together in a heated source chamber. It would have been prima facie obvious to one skilled in the art to use Dauelsberg's two-material vaporizer for depositing one of the plural layers suggested by Forrest (I and II). Also, Konuma teaches (see Fig. 7B) that it was known to be desirable to form a plural layer organic EL device wherein an Alq₃/DCM-1 mixed layer is formed on top of an Alq₃ layer. It would have been prima facie obvious to form the Alg₃ layer of Konuma with a vaporizer of the type shown in Fig. 8 of Jurgensen and to form the Alg₃/DCM-1 mixed layer with a vaporizer of the type shown in Fig. 9 of Dauelsberg, because both types of vaporizer were known in the prior art to be useful for depositing organic layers for organic El devices of the type shown in Fig. 7B of Konuma.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Richard Bueker whose telephone number is (571) 272-1431. The examiner can normally be reached on 9 AM - 5:30 PM, Monday-Friday.

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If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Parvis Hassanzadeh can be reached on (571) 272-1435. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Richard Bueker
Primary Examiner
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